

DETAILED ACTION

Response to Amendment

1. Applicant's amendments, filed 12/15/2009, have been fully considered and reviewed by the examiner. The examiner notes the amendment to claim 1 and the addition of new claim 40. Claims 1-20 and 34-40 are pending in the instant application.
2. The declaration under 37 CFR 1.132 filed 12/15/2009 is insufficient to overcome the rejection of claims as set forth in the last Office action because the affidavit fails to provide factual evidence to support the positions set forth therein.

Response to Arguments

3. Applicant's arguments are deemed moot in view of the Examiner's Amendment below.

EXAMINER'S AMENDMENT

4. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it **MUST** be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Aaron Kamlay on 2/5/2010.

The application has been amended as follows:

IN THE CLAIMS

Claim 1, first line, please replace "film" with "layer"

Claim 1, second line, after "organic material on a " please insert "surface of a "

Claim 1, line 8, after "forming" please replace "a plurality of separate films of organic material on the substrate" with "the layer of the organic material on the surface of the substrate, the layer comprising a plurality of separate films; and"

Claim 1, lines 10-13, please replace "wherein a region between the nozzle and the substrate surrounding the carrier gas has a dynamic pressure of at least 1 Torr" with "based upon the molecular mass of the carrier gas, the molecular mass of the organic material, the mean free path of the ejected material, or a combination thereof, selecting a separation s between the nozzle and the substrate and a downstream pressure P_L sufficient to create a dynamic pressure surrounding the carrier gas in a region between the nozzle and the substrate of at least 1 Torr"

Claim 4, after further comprising, please replace "ejecting a guard flow from the nozzle" with "providing a guard flow surrounding the ejected material"

Claim 6, after further comprising, please replace "ejected from the nozzle" with "surrounding the ejected material"

Claim 11, first line, please replace "film" with "layer"

Claim 11, second line, after "organic material on a " please insert "surface of a "

Claim 11, line 8, after "separated from nozzle" please replace ", forming a plurality of separate films of organic material on the substrate" with "to form the

patterned layer of organic material, the layer comprising a plurality of separate films on the surface of the substrate".

Claim 36, line 1, after "plurality of "please insert "separate "

Claim 37, line 1, after "plurality of "please insert "separate "

5. The following is an examiner's statement of reasons for allowance: None of the prior art cited or reviewed by the examiner alone or in combination reasonably teaches or suggests depending on the claimed process parameters selecting a separation s between the nozzle and the substrate and a downstream pressure P_L sufficient to create a dynamic pressure surrounding the carrier gas in a region between the nozzle and the substrate of at least 1 Torr. Specifically, while Stein references disclose a simulation, this simulation merely suggests to one of ordinary skill in the art to use the parameters are taught in the reference and there is no suggestion of successful deposition by depending on certain claimed parameters and then selecting certain parameters to provide a dynamic pressure surrounding the carrier gas as claimed. Additionally, the claims are allowed over the applied prior art for at least the reasons set forth in the section 1 above and the applicant's remarks date 12/15/09 and the affidavit provided 12/15/2009.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to DAVID TUROCY whose telephone number is (571)272-2940. The examiner can normally be reached on Tuesday, Thursday, and Friday from 7 a.m. - 6 p.m., Monday and Wednesday 5-8 pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Timothy Meeks can be reached on (571) 272-1423. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

/David Turocy/
Primary Examiner, Art Unit 1792